Form PTO-1449 (modified)	Atty. Docket No. 2008.005782	Serial No. ~~Unknown~~ 10/680,581
List of Patents and Publications for Applicant's INFORMATION DISCLOSURE STATEMENT	Applicants Dinesh Chopra	
(Use several sheets if necessary)	Filing Date: 10/07/03 ~~Concurrently Herewith~~	Group: ~~Unknown~~ 2812

U.S. Patent Documents	Foreign Patent Documents	Other Art
See Page 1	*See Page 1*	*See Page 1*

U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
SDE	A1	6,268,291 B1	7/31/01	Andricacos *et al.*	438	694	
	A2	6,297,155 B1	10/02/01	Simpson *et al.*	438	687	
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	A7	2002/0115292 A1	8/22/02	Andricacos *et al.*	438	687	7/26/01

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
	B1						
	B2						
	B3						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
SDE	C1	Shibata *et al.*, "Lithography-less Ion Implantation Technology for Agile Fab," ULVAC Confidential
SDE	C2	Shibata *et al.*, "Stencil Mask Ion Implantation Technology for High Performance MOSFETs," 2000 IEEE
	~~C3~~	

EXAMINER: Stanetta Isaac | DATE CONSIDERED: 9/26/06

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